

Exclusive offering by **GE Semi** and **LIQUIDITY SERVICES**

Complete *Silicon Epitaxial Wafer Fab*

GESemi and Liquidity Services are pleased to exclusively present the opportunity to acquire IQE Silicon Epitaxial Wafer Fab located in Cardiff, Wales, UK.

This approximately 12,400-square-foot facility boasts an installed capacity of over 800 wafers per day, operating at 80% availability.

Manufacturing of advanced silicon epitaxial wafers for a diverse array of technological applications.

Offers are being reviewed for both complete fab and individual equipment!



Cleanroom

Class 1: Approximately 1,120 sq. ft. Includes Wafer Clean Room, Measurement Room, Central Clean Room, and Air Shower.

Class 1000: Approximately 930 sq. ft. Includes Changing Room, North Grey Room, and South Grey Room.

Production Capacity

The fab can achieve a production rate of 800 wafers per day at 80% availability, based on a typical DCS process.

Geometries

The facility supports nanometer layers up to 140 microns across multiple customer geometries. It operates at temperatures ranging from 300 to 1190°C and pressures from 5 Torr to ATM across all tools.

Process Technologies

The fab utilizes various process technologies, including CMOS, Photonics, Silicon on Sapphire, Germanium on Silicon, Selective SiGe, SiGe, Selective Ge, Selective Silicon, Strained Silicon, and Ge on GaAs. It also supports in situ doping with AsH₃, PH₃, and B₂H₆ across a range of concentrations.

Year Built

The IQE facility was established in 2000. The staff collectively has over 100 years of semiconductor experience.

Equipment

The facility houses over 40 pieces of equipment, including five ASM E2000 RP Epi Reactors. Additionally, it has over 1,000 spare parts, including kits for each reactor to be configured for 100mm, 150mm, and 200mm wafer sizes.

For further details on the equipment, facility, patents and intellectual property (IP), please inquire.

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Complete *Silicon Epitaxial Wafer Fab* - Asset List

Manufacturer	Model	Description	Quantity
ASM	E2000	RP Epitaxial Reactor	5
Binder	FD53	Oven	2
Diener Electronics	Nano	Plasma	1
Chemical Safety Tech Inc	----	Chemical storage cabinets	2
Libratherm	PID-8000	Temperature controller	1
TECARC	XC600	Welding Water cooler	1
Spectra	MINI-LAB	Mini-Lab	1
Edwards Limited	IGX600M	Vacuum Pump	1
Ebara	A70W	Dry Pump	7
Edwards	iXH1220HTX	Dry Pump	2
Warco	WM-16 VS MILL	Milling Machine	1
Warco	WM280V	Lathe	1
Binder	----	Oven	1
MTI Corporation	VBF-1200	Compact Vacuum Chamber Furnace	1
Semitool	280S	Single SRD	1
MGI	ET2000	Wafer Transfer System	2
DekTak	DekTak 8	Profilometer	1
Accent	QS-2200A	Biorad	1
Leica	INS3000	Microscope	1
SDI	FAaST 230-USPV	SPV	1
Tencor	RS75 Omnimap	Resistivity Mapper	1
SVG	8620SSC	Wafer Scrubber	1
Airgard	STS-6-2A	Wet Gas Abatement System	2
Airgard	Cyclone	Wet Gas Abatement System	1
SemiAn	SBW 200-CE	Wet/Dry/Wet Gas Abatement System	5
DOW Electronic Materials	Mark III	Vapourstation	1
PMS	Airnet 310-4	Particle Monitoring Unit	3
Spare Parts	Various	Comprehensive List Available Upon Request	1,000+

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